ELECTRICAL ENGINEERING **& COMPUTER SCIENCE**

A Micro Oven-Control System for Inertial Sensors

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Problem Definition

- Navigation system using MEMS inertial sensors greatly suffers from temperature change
- For example, position error of one of the best MEMS gyroscopes, Challoner PLANS 2014, is < 1m at 100s at RT, while it increased to > 50m at 100s with 3°C/min thermal shock

Other sensors show degraded much inertial



performances with thermal shock

Oven-Control System Diagram



- Lease mean square (LMS) and random forest (RF) compensation algorithms are used to minimize residual bias errors









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